

Question #1

- ◆ **Will sub-WL complexity force costly new abstractions? Will we move to lithography simulators inside layout tools?**
 - **Name 3 “rules” or “methodologies” that will be the most effective in keeping process “under the rug”.**

Question #2

- ◆ **Is Layout = Silicon really a must ? (Isn't our real goal Functional Design = Realization ?)**
 - **Is there a brave new future world of radically different layout tools, extraction models, circuit design styles ?**
 - **Will this be driven by the mask verification bottleneck ?**

Question #3

- ◆ **What are implications of Sub-WL for reuse-based design ?**
 - **cell-based layout and verification, hard-IP reuse ?**
 - **(density control, optics flavors...)**

Question #4

- ◆ **Today “ECAD” ends at “GDSII Out”. How will things be different 5 years from now ?**

Question #5

- ◆ **So who owns the scrap ? (masks, silicon)**

Question #6

- ◆ **Will Sub-WL be a bonanza or a disaster for:**
 - **physical+performance verification and analysis**
 - **custom layout + cell generation tools**
 - **3rd-party hard IP providers**
 - **foundries**
 - **... ?**